Patent 25-107

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In re P	atent Ap	oplication of	of:) [.]				
Nobuo YAMGUCHI) Group Ar	t Unit: 2812		<i>^</i>		
Application No.: 09/895,403) Examiner	: Unassigned	2			
Filed:	l: July 3, 2001))			80, 8 1	\)
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	[X]	No additi	onal fee for subr	nission of	an IDS is requ	ıired.			
	[]	The fee o	f \$240.00 (126)	as set fort	h in 37 C.F.R	. § 1.17(p) is a	lso enclos	ed.	
	[]	A certific	ation under 37 C	C.F.R. § 1	.97(e) is also	enclosed.			
	[] A certification under 37 C.F.R. § 1.97(e), a petition requesting consideration of the information disclosure statement, and the petition fee of \$130.00 (122) as set forth in 37 C.F.R. § 1.17(i) are also enclosed.								
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					pectfully subm	nitted, SWECKER & MA	ATHIS, L.L	.P. ·	
Alexan	ox 1404 dria, Vi 36-6620	rginia 223	13-1404	Ву:	William C. Registration	Charland Rowland No. 30,888	2		
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INFORMATION DISCLOSURE STATEMENT TRANSMITTAL LETTER							
		missioner for Patents O.C. 20231					
Sir:							
above-		ed is an Information Disc d patent application.	osure Statement and acc	ompanying form I	PTO-1449 for the		
	[X]	No additional fee for su	mission of an IDS is req	լuired.			
	[]	The fee of \$240.00 (126	as set forth in 37 C.F.I	R. § 1.17(p) is also	o enclosed.		
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	[] Charge \$ to Deposit Account No. 02-4800 for the fee due.						
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			Respectfully subs BURNS, DOANE,	nitted, SWECKER & MAT	HIS, L.L.P.		
P.O. Box 1404 By: Alexandria, Virginia 22313-1404 (703) 836-6620			By: <u>William</u> William C. Registration	Rowland n No. 30,888			

Date: 9-24-01

UNITED STATES PATENT AND TRADEMARK OFFICE

TO SEP SEVED In re Patent Application of:)) Nobuo YAMGUCHI Group Art Unit: 2812 Examiner: Unassigned Application No.: 09/895,403 RECEIVED "00. OCT 3 1 2001 TC 1700 Filed: July 3, 2001 **ELECTROSTATIC ATTRACTION** For: MECHANISM, SURFACE PROCESSING METHOD AND SURFACE PROCESSING DEVICE

INFORMATION DISCLOSURE STATEMENT

Assistant Commissioner for Patents Washington, D.C. 20231

Sir:

In accordance with the duty of disclosure as set forth in 37 C.F.R. § 1.56, Applicants hereby submit the following information in conformance with 37 C.F.R. §§ 1.97 and 1.98. Pursuant to 37 C.F.R. § 1.98, a copy of each of the documents cited is enclosed.

The filing of this Information Disclosure Statement shall not be construed as a representation that a prior art search has been made.

In addition, the filing of this Information Disclosure Statement shall not be construed to be an admission that each of the references submitted herewith is in fact prior art with respect to the present application, or that each of the references is considered to be material to patentability as defined in § 1.56(b).

The documents are being submitted within 3 months of the filing and before the first Office Action on the merits, whichever is later, therefore no fee or certification is required under 37 C.F.R. § 1.97(b).

To assist the Examiner, the documents are listed on the attached form PTO-1449. It is respectfully requested that an Examiner initialed copy of this form be returned to the undersigned.

Respectfully submitted,

BURNS, DOANE, SWECKER & MATHIS, L.L.P.

Date: 9-24-01

William C. Rowland

Registration No. 30,888

P.O. Box 1404 Alexandria, Virginia 22313-1404 (703) 836-6620

INFORMATION DISCLOSURE
STATEMENT BY APPLICANT

ATTORNEY'S DKT No.	APPLICATION NO.
001425-107	09/895,403
APPLICANT	
Nobuo YAMGUCHI	
FILING DATE	GROUP
July 3, 2001	2812

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EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and _not considered. Include copy of this form with next communication to applicant. SEND TO: Assistant Commissioner for Patents, Washington, D.C. 20231.